

LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Vishnu K. Agarwal et alFILING DATE
January 15, 2002GROUP
2813

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
yk	AA 6,204,070	03/2001	Kim			
	AB 6,207,487	03/2001	Kim et al			
	AC 6,391,803	05/2002	Kim et al			
yk	AD 6,420,230	07/2002	Derderian			
	AE					
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	AL					

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
yk	AM KR 2002002157A	01/2002	Korea				
	AN						
	AO						
	AP						
	AQ						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

AR		
AS		
AT		

EXAMINER

DATE CONSIDERED

12/3/03

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1913		Priority SERIAL NO. 09653.156		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Vishnu K. Agarwal		Priority FILING DATE August 31, 2000		
				Priority GROUP 2813				
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
YH	AA	6,180,481	01/2001	Deboer et al				
	AB	6,218,256	04/2001	Agarwal				
	AC	6,104,049	08/2000	Solayappan et al				
	AD	6,180,447	01/2001	Park et al				
	AE	6,274,428	08/2001	Wu				
	AF	6,124,158	09/2000	Dautartas et al				
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	AJ	6,204,172	09/1998	Marsh				
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YH	AR		A.W. Ott, et al., "Atomic Layer Controlled Deposition of Al ₂ O ₃ Films Using Binary Reaction Sequence Chemistry", Applied Surface Science (107), 1996, pps. 128-136.					
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EXAMINER DATE CONSIDERED 7/19/02								
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	09/653,149		Derderian			08/31/00
	AB	09/652,532		Derderian (as filed and amended 11/29/01)			08/31/00
	AC						
	AD						
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	AM						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	<div style="text-align: center;">Translation</div> <div style="display: flex; justify-content: space-around; font-size: small;"> Yes No </div>
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
EXAMINER				DATE CONSIDERED			
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